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UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Im-soo PARK, et al

Art Unit: 1746

Serial No.: 10/685,515

Examiner: Saeed T. Chaudhry

Filed: October 16, 2003

Confirmation No.: 8169

For: APPARATUS FOR CLEANING
SEMICONDUCTOR WAFER
INCLUDING HEATING USING A LIGHT
SOURCE AND METHOD FOR
CLEANING WAFER USING THE SAME
(AS AMENDED)

Attorney Docket No.: 249/255 DIV

19
3/14/06

AMENDMENT UNDER 37 C.F.R. § 1.116

Mail Stop: BOX AF
Commissioner for Patents
United States Patent and Trademark Office
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

INTRODUCTORY COMMENTS

In response to the Office Action Made Final, dated January 9, 2006, the following amendments and remarks are respectfully submitted in connection with the above-identified application:

Amendments to the Claims are reflected in a listing of claims, which begins on page 2 of this paper.

Remarks begin on page 5 of this paper.